ELTX

University of Mumbai Examinations Summer 2022

Program: Electronics Engineering Curriculum Scheme: Rev 2016 Examination: BE Semester VIII

QP code - 94023

Course Code: ELX DLO8042

Time: 2-hour 30 minutes

Course Name: MEMS Technology

Max. Marks: 80

compulsory and carry equal marks 1. DMD Stands for Option A: Discrete Mirror Device Option B: Digital Mirror Device Option C: Digital Mirror Device Option D: Discrete Micromirror Device 2. Which of the following is not a piezo electric sensor? Option A: PZT Option B: Roscelle salt Option C: Quartz Option D: Microheater 3. What is Piezo resistivity? Option A: Electrical voltage changes in response to mechanical stress Option B: Electrical resistance changes in response to mechanical stress Option D: Producing an electric field when subjected to an external force 4. An Alloy that can be deformed when cold but returns to its pre-deformed shape when heated? Option B: Metal Option C: Shape memory alloy Option C: Shape memory alloy Option C: Shape memory alloy Option C: Slope Option C: Piezoresistive		Change the same to the country of th				
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A ST TONG TO SERVICE AND SERVI	7 7 7 5 10 7 7 7 7 5 10					
Toll is shape.	the state of the s					
Option A: Square	Option A;	Square				

Option B:	Circular at the end
Option C:	Trapezoidal
Option D:	Oval
8.	To deposit polymers which deposition method is used?
Option A:	CVD
Option B:	LPCVD
Option C:	HPCVD
Option D:	PECVD
9.	What is Sputtering?
Option A:	Process of Cleaning
Option B:	Process of Deposition
Option C:	Process of Diffusion
Option D:	Process of Oxidation
10.	The principal microfabrication process used in bulk manufacturing is
Option A:	Etching
Option B:	chemical vapour deposition
Option C:	physical vapour deposition
Option D:	Diffusion

Q2 (20 Marks)	Solve any Four out of Six 5 marks each (All Questions carry equal marks)
A	Discuss the role of SU8 in MEMS applications.
В	What is MEMS? What is significant difference between Microelectronics and Microsystem?
С	Explain Air-Bag deployment system in brief.
D	Differentiate between bulk and surface micro machining.
E	What are different types of pressure sensors
F	Define the term TCR. Also describe the method of characterization of TCR.

Q3 (20 Marks)	Solve any Two Questions out of Three 10 marks each (All Questions carry equal marks)
A	Discuss the process flow of Photolithography. Explain the types of photoresists used.
	What are micro-actuators pertaining to MEMS Technology? Give two examples.
N. C	Describe the representative process flow for fabricating the micro-heater. Also explain the operating principle of this MEMS device in detail with its analytical expression.

(20 Marks)	Solve any Two Questions out of Three 10 marks each (All Questions carry equal marks)
	What is MEMS micromachining? Explain in details fabrication process flow of LIGA. Why electroplating is necessary in LIGA process.
	What do you mean by wafer bonding? Explain with neat diagram, different wafer bonding techniques.
c	List and explain all the types of failure mechanisms used in MEMS.

University of Mumbai

Examinations Summer 2022

Program: Electronics Engineering

Curriculum Scheme: Rev 2016 Examination: BE Semester: VIII

Course Code: ELXDLO_8044

code- 93808

Time: 2 hour 30 minutes

Course Name: Digital Image Processing

Max. Marks: 80

Q1.	Choose the correct option for following questions. All the Questions are			
1.	Assuming that a 10m high structure is observed from a distance of 20m. What is the size of retinal image? Assume that the distance is the size of 20m.			
Option A	: 8.5 mm			
Option B	: 34mm			
Option C	0.118mm			
Option D:	34cm			
2.	Which of the following is not a point processing operation?			
Option A:	Tistogram Processing			
Option B:	Digital Negative			
Option C:	Contrast Stretching			
Option D:	Thresholding			
3.	If the original image is rotated by 450			
	If the original image is rotated by 45° in spatial domain the spectrum gets rotated by			
Option A:	45°			
Option B:	65°			
Option C:	09			
Option D:	1800			
option b.	100			
4. 3	Thinning operation is used to remove the pixels			
Option A:	image pixels			
Option B:	foreground			
Option C:	object			
Option D:	back ground			
√ ₹ 5 ₹ 8€	Identify the operator X, Where X=[0 -1 0; -1 4 -1; 0 -1 0]			
Option A:	Sobel edge operator			
Option B:	Prewitt edge operator			
Option C:	Gradient operator			
Option D:	Laplacian operator			
6.	Mask used for line detection is			
Option A:	Gaussian Gaussian			
Option B:	Laplacian			
Option C:	Ideal			
Option D:	Butterworth			
>	Danctwolfil			
7.	Basis images can be generated by			
Option A:	Symmetric matrices			
	Unitary matrices			
Tricki.	Non symmetric matrices			

Option D:	Circulant matrices
8.	Which of the following transform give multiresolutional analysis?
Option A:	Discrete Fourier Transform
Option B:	Discrete Cosine Transform
Option C:	Fast Fourier Transform
Option D:	Discrete Wavelet Transform
9.	Which block in image processing system introduces lossy compression?
Option A:	Mapper
Option B:	Quantizer
Option C:	Variable length coding
Option D:	negative
10.	IGS code for 100, 110 are 기가
Option A:	1000, 0110
Option B:	0110, 0111
Option C:	0110, 1000
Option D:	0110,0111

Q2.							ye ^r i yi		
A	Solve any Two		1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1				S	5 mar	cs each
i.	Explain digital image sampling and quantization								
ii.	Explain Hough transform for ed	***))			
iii,	Give Laplacian operator and ex	plain how	it is u	sed to o	letect ed	ges.			
В	Solve any One								cs each
i	Apply the following image en segment. (i) Digital Negative (ii) Thresholding (T = 5) (iii) Intensity level slicing w	ith and w				~	·	-	l image
ii.	The grey level distribution of equalization and plot histogram histogram equalization.								
	Gray Level	0	1	2	3	4	5	6	7
	Frequency of Occurrence	100	250	100	300	150	0	0	0

Q3.	
A	Solve any Two 5 marks each
i,	Explain Hit - and - Miss Transform.
ii,	Write short note on Homomorphic filtering.
iii.	Explain the following morphological operations:- i. Opening ii. Closing
В	Solve any One 10 marks each
i.	What is image segmentation? Explain with example segmentation based on similarities.
ii.	Name and explain different types of data redundancies in digital image. Classify the following compression techniques in to lossy and loss less:-
	(i) IGS coding (ii) Run length coding (iv) DPCM coding
	(iii) Transform coding (iv) DPCM coding

Q4.	
A	Solve any Two 5 marks each
i.	Explain the procedure of Huffman coding.
ii.	State the expression for one dimensional Discrete Cosine Transform. Give the importance of DCT in image compression.
iii.	Explain Discrete Wavelet Transform.
В	Solve any One 10 marks each
i.	What is Hadamard Transform? State its properties. Calculate the Hadamard Transform of following image.
	2 1 2 1
	1 2 3 2
	2 3 4 3
	1 2 3 2
ii.	Explain with block diagram JPEG encoder and decoder.

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University of Mumbai

Summer Examination 2022

Program: BE Electronics Engineering

Curriculum Scheme: Rev2016 Examination: BE Semester VIII

Course Code: ELX 801 and Course Name: Internet of Things

Time: 2-hour 30 mins

Max. Marks:80

01	Choose the correct option for following questions. All the Questions are					
Q1.	compulsory and carry equal marks					
1.	Communication Environments in case of data routing over the Web for connected					
	devices are Classified into which of the following options:					
Option A:	CoRE Environment and Unconstrained Environment					
Option B:	CoRE Environment and Constrained Environment					
Option C:	Casual Environment and Bock Environment					
Option D:	Free Space Environment and Atmospheric Environment					
2.	SOAP is a protocol for:					
Option A:	exchange of objects between applications using XML					
Option B:	exchange of objects between applications using text					
Option C:	exchange of control information between the sender and receiver					
Option D:	exchange of KEYS between the sender and receiver					
3.	CoAP-MQ broker:					
Option A:	Acts as a firewall					
Option B:	senses data from various sensors					
Option C:	store only control messages intended to other nodes.					
Option D:	enables web client publishing of updates to the endpoints					
4.	DHCP facilitates:					
Option A:	Static IP Addressing in any networks					
Option B:	Dynamic IP Addressing in any network					
Option C:	MAC ID allotment to all devices connected in the network					
Option D:	The generation of IO port numbers					
5.	AMQP is designed for:					
Option A:	Control data transfer					
Option B:	LANs and WANs					
Option C:	Business Messaging					
Option D:	Spatial co-ordinate node selection in WSN					
6.	UDP protocol is used for:					
Option A:	acknowledged data flow					
Option B:	unacknowledged data flow					
Option C:	Reliable communication					
Option D:	full duplex secured communication					
7.	Observer nodes can:					
Option A:	Process information and use it for various applications but they do not perform any control functions.					
Option B:	Process information and performs control Actions.					

Ontion C	Perform only control Actions whenever required.			
Option C:				
Option D:	Cannot perform processing operation but acts as a repeater node.			
8.	A Home Automation System Application will have following set of services:			
Option A:	Controller service, Mode Service ,State Service			
Option B:	Controller Service only			
Option C:	Mode Service and State Service only			
Option D:	Controller service and State Service only			
9.	Which sensors will not be used for weather monitoring system			
Option A:	Temperature sensor			
Option B:	Pressure sensor			
Option C:	Acceleration sensor			
Option D:	Relative Humidity Sensor			

10.	Online Transaction Processing (OLTP) is used in:			
Option A:	Internet of automatic chocolate vending machines			
Option B:	Internet of ATMs			
Option C:	Internet of RFIDs			
Option D:	Internet of streetlights			

Q2. (20 Marks)		
A	Solve any Two	5 marks each
i	Draw and explain IoT Level 1, IoT Level 5 and I	
ii 22	List the various REST Architectural constraints a detail	and explain any two in
iii	List the features in Xively cloud platform.	
В	Solve any One	10 marks each
· i	Explain the various design methodology steps in sequence.	
ii	Write a short note on i)LPWAN ii) NBIoT	

Q3. (20 Marks)		
A	DOX CONTROL OF THE PROPERTY OF	5 marks each
ester attendigen i die	Explain the various Data Categorizations for storage in IoT Systems.	
ii	List the semantics followed by NOSQL instead of ACID rules that are followed in normal databases.	
iii	Compare the various types of OLTP available.	
В	Solve any one 1	0 marks each
i	Explain the CoAP and AMQP Protocol.	
ii	Draw and detail the deployment design of any weather me System.	onitoring IoT

Q4. (20 Marks)	
A	Solve any Two 5 marks each
i	Explain how the following electrical parameters are used as a part of sensing Technology: a) Capacitance and b) reverse saturation current of PN Junction
ii	What are the Characteristics of IoT?
iii	What are the advantages and Concerns of Cloud Computing?
В	Solve any One 10 marks each
i	Write a short note on i)Server Management ii)Spatial Storage
ii	Explain the MQTT protocol with respect to any one loT application.



University of Mumbai Examination May-June 2022

Program: Electronics Engineering

Curriculum Scheme: Rev2016 Examination: BE Semester VIII

Course Code: ELX802 and Course Name: AnalogandMixedVLSIDesign

Time: 2 hours 30Minutes Max. Marks: 80

Q1.	Choose the correct option for following questions. All the Questions are compulsory and carry equal marks
Q1,	Marks
1.	In current mirror circuit, the first MOSFET (which copy current from reference) is operating in which region?
Option A:	Linear
Option B:	Saturation
Option C:	Cut-off
Option D:	deep triode region
2.	Which of the following statement is true in case of Base to Emitter voltage (V_{BE}) of BJT?
Option A:	It has negative temperature coefficient
Option B:	It has positive temperature coefficient
Option C:	It has both temperature coefficient
Option D:	It is equal to $(I_B)^2$
3.	The condition for MOSFET to be in deep triode region is
Option A:	$V_{DS} << 2(V_{GS} - V_{TH})$
Option B:	$V_{DS} \gg 2(V_{GS} - V_{TH})$
Option C: 3	$V_{DS} \ll (V_{GS} - V_{TH})$
Option D:	$V_{DS} \gg (V_{CS} - V_{TH})$
4	Thermal noise is generated from MOSFET by
Option A.	Conduction of charge carriers in the channel
Option B.	Electric field across the gate and channel
Option C:	Capacitance of the gate oxide
Option D:	Substrate bias effect
5.	CS amplifier with Source degeneration voltage gain
Option A:	increases
Option B:	decreases
Option C:	moderate
Option D:	zero

6,	ro is the internal resistance of a MOSFET is equal to
Option A:	1/\lambda I _D
Option B:	\mathcal{N}_{D}
Option C:	$I_{\rm D}/\lambda$
Option D:	λI_{D}
7.	In Switched Capacitor circuits, to achieve a higher sampling speed, & must be used.
Option A:	A small aspect ratio, a small capacitor
Option B:	A Large aspect ratio, a large capacitor
Option C:	A small aspect ratio, a large capacitor
Option D:	A Large aspect ratio, a small capacitor
8.	Which of the following is the main advantage of semicustom design approach
	over full custom design?
Option A:	Use of standard cells to reduce design time and complexity
Option B:	High performance
Option C:	More complexity
Option D:	High Speed
9.	What is the function of low pass filter in phase-locked loop (PLL) circuit?
Option A:	Improves low frequency noise
Option B:	Removes high frequency noise
Option C:	Tracks the voltage changes
Option D:	Changes the input frequency
10.	The resolution of 8-bit DAC/ADC is
Option A:	562
Option B:	256
Option C:	625
Option,D:	128

Q2	Solve any Four out of Six 5 marks each
A	Explain trade-offs in analog design with the help of analog design octagon.
В	What are the disadvantages of basic current mirror circuit and how it is overcome in cascode current mirror?
C	Explain the concept of switched capacitor circuit.
D	Which errors are contributed by charge injection mechanism in MOS sampling circuits?
Ē	Compare performance parameters of various op-amp topologies.
F	Explain behaviour of g _m as function of below parameters 1. Overdrive voltage with W/L constant. 2. Overdrive voltage with I _D constant

Q3	Solve any two out of three	10 marks each
Α.	Derive the expression of voltage gain and output resistance	of the source
/1	follower circuit.	
13	What is a bandgap reference? Describe methods of implen	nentation of band gap
В	references.	
	Explain AMS design flow in VLSI circuit. Compare full cu	istom and semi-
	custom design.	

Q4	Solve any two out of three	10 marks each
A	Draw and explain charge pump PLL circuit	
В	What are the various types of ADC architectures? architectures in detail.	Explain any two
С	Derive the equation of Differential gain and Common mode amplifier.	gain of differential